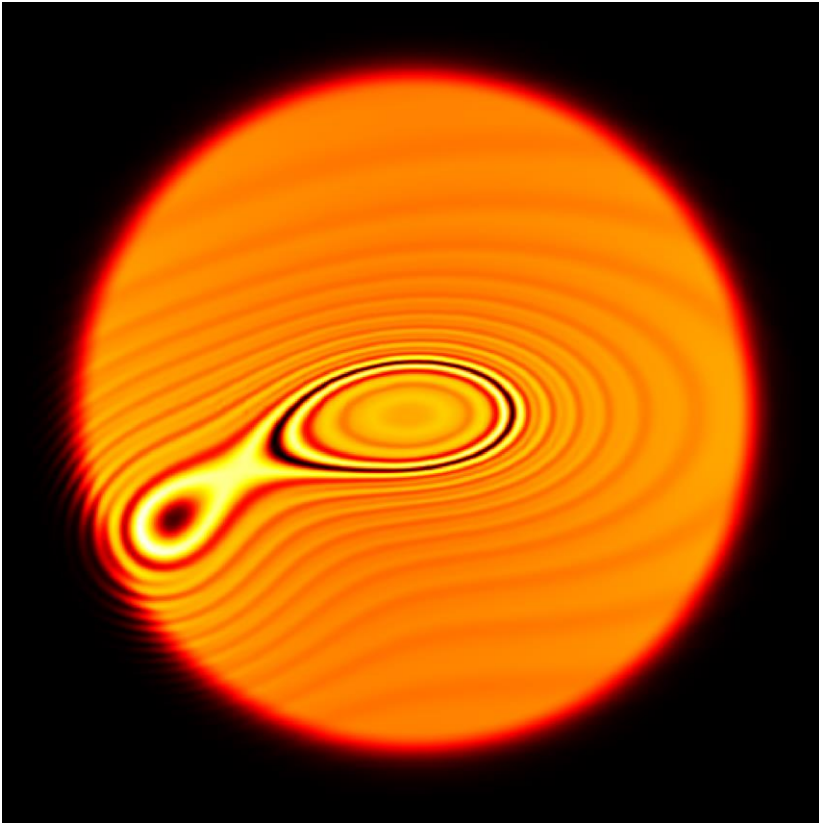


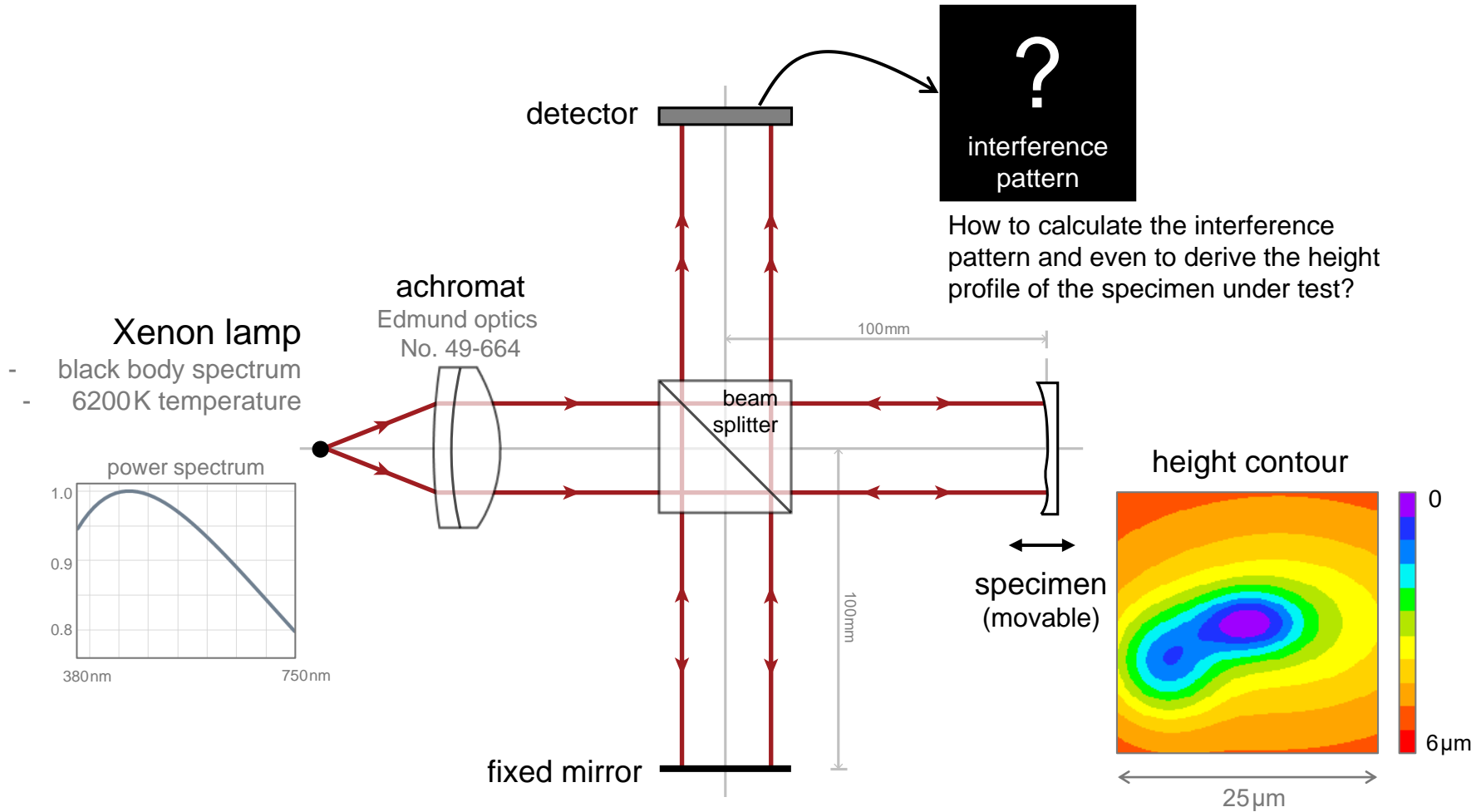
Optical Topography Scanning Interferometry

Abstract

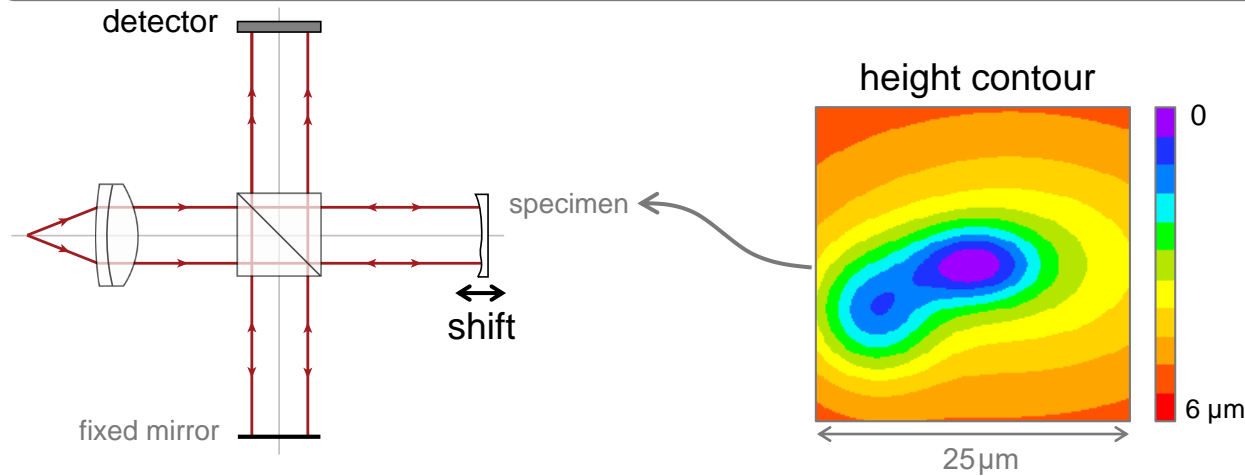
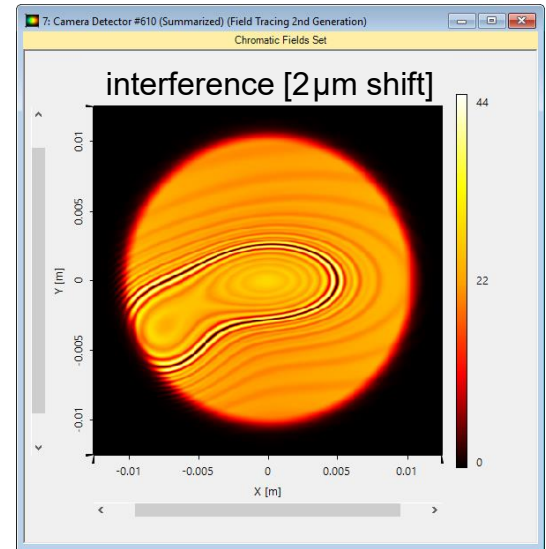
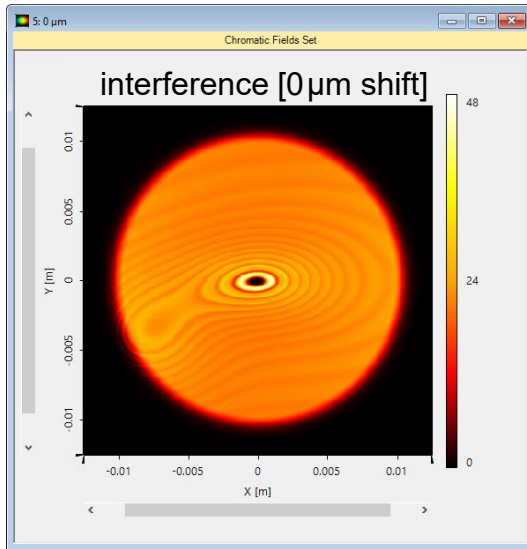


Scanning interferometry is the technique for performing surface height measurement. By exploiting the low coherence of white light source, interference pattern appears only when the path length difference is within the coherent length. Therefore, it enables precise microscopic measurement. Together with a Xenon lamp, a Michelson interferometer is built up and used to measure a specimen with smoothly varying front surface.

Modeling Task



Results



Contour lines of interference corresponds to the height contour of the specimen under test.

Document Information

title	Optical Topography Scanning Interferometry
version	1.0
VL version used for simulations	7.0.3.4
category	Application Use Case
